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Sommario/riassunto	Now available in softcover, this book closely examines the enabling technologies for the fabrication of micro- and nanodevices. Divided into two clearly structured sections, the first begins with an insider's view of industrial MEMS commercialization, followed by chapters on capacitive interfaces for MEMS, packaging issues of micro- and nanosystems, MEMS contributions to high frequency integrated resonators and filters, as well as the uses of MEMS in mass data storage and electrochemical imaging by means of scanning micro- and nanoprobe. The second section on nanodevices first tackles the